Surface Roughness Investigations on Nb Samples using Optical Profilometry

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Nb samples from: A. Matheisen, D. Reschke, X. Singer, J. Ziegler (DESY) P. Kneisel (TJNAF)

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Motivation and strategy

- Enhanced field emission (EFE) is caused by particulates or scratches [1]
- Quenches and high-field Q-drop might depend on surface roughness [2]
- Number density of particulates can be much reduced by HPR [3], DIC [4] and clean room assembly, but influence of surface irregularities on EFE and quenches of poly/single crystalline EP/BCP Nb has been less studied
 - [1] A. Dangwal et al., Phys. Rev. ST Accel. Beams 12, 023501 (2009).
 - [2] J.Knobloch et al., Proc. 9th Workshop on SRF (1999), p.77.
 - [3] P. Kneisel et al., Proc. 7th Workshop on SRF (1995), p.311.
 - [4] A. Dangwal et al., J. Appl. Phys. 102, 044903 (2007).

>1-st step S

Systematic measurements of average surface roughness and local defect geometry for typical Nb samples by means of optical profilometry and AFM

Localization and characterization of effective field emitters (E_{on} (1 nA), β , S) on the same Nb samples after HPR with FESM and in-situ SEM imaging

3-rd step

Ex-situ HRSEM/EDX identification of emitting defects and investigation of the correlation between EFE parameters and geometry of defects







Surface roughness measurement techniques



Optical profilometer (OP)

white light irradiation and spectral reflection

- fast scanning speed (100×100 pixel per min)
- samples up to 20×20 cm² and 5 cm height
- 2 µm lateral and 3 nm height resolution
- atomic force microscope (AFM) operated in contact or non-contact mode
 - 2 μm positioning accuracy within OP scan
 - 34×34 µm² scanning range
 - 3 nm lateral and 1 nm height resolution
- CCD camera for positioning control
- granite plate with an active damping system for undisturbed measurement at nm scale
- clean laminar air flow from the back to reduce particulate contamination



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Average surface roughness and electric field enhancement

Definition of average surface roughness

$$R_a = \frac{1}{n \cdot m} \sum_{i=1}^n \sum_{j=1}^m \left| z(x_i, y_j) - \overline{z} \right|$$

$$R_q = \sqrt{\frac{1}{n \cdot m} \sum_{i=1}^n \sum_{j=1}^m \left(z(x_i, y_j) - \overline{z} \right)^2}$$

 $z(x_i, y_j)$ = actual height value of profile n, m = pixel number in x and y direction \overline{z} = average height value Estimated electric field enhancement for protrusions, activated particulates (initially MIM) and scratches:

$$\beta_E = \frac{E_L}{E_S} \approx \frac{h}{r}$$

ightarrow emission area $S pprox 2\pi r^2$

 E_L = local electric field on defect E_S = electric field on flat surface h = height of defect r = curvature radius



Results on polycrystalline Nb samples from DESY



Nb samples were assembled into the coupler port and BCP/EP/HPR processed with 9-cell cavities

^{um} 4 types of surface irregularities found with OP:

- particulates
- scratches
- grain boundaries
- round hills and holes





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OP results on polycrystalline Nb samples from DESY

Scratches

G. Müller, 02.03.2011





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OP results on polycrystalline Nb samples from DESY

Grain boundaries



and modified chemical reactions during EP



height < 17 µm
size 10 - 440 µm
$$R_a = 0.295 µm$$

 $R_q = 0.489 µm$
 $\beta_{E,max} < 4$

only weak EFE expected

but probably high magnetic field enhancement β_M ?





EFE/SEM/OP results on polycrystalline HPR-Nb samples



EFE/SEM results on polycrystalline Nb samples







In most EFE locations it is difficult to identify the exact emitter position due to complex geometry of defects

AFM measurements are required for β_{geo} estimation of small structures



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Results on single crystalline Nb samples from TJNAF

In order to investigate the possible advantages of single crystalline Nb for SRF, 4 round samples with varying BCP damage layer removal (20, 40, 80, 120 μ m) and two marks at the edge for clear orientation have been measured with OP.





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OP of single crystal Nb for different BCP layer removal

scanned area 1×1 mm²



Average surface roughness of single crystal BCP-Nb

Each point based on profiles in 10 different defect-free areas of 1 mm² BCP roughness



G. Müller, 02.03.2011

Regular pit-like features on single crystal BCP-Nb



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Milano Meeting

COLLABORATION

Few local defects found on single crystal BCP-Nb

All samples showed a few local defects (> 5 μ m) which might cause EFE



BCP 40 μ m accumulated particulates average size ~ 22 μ m, Δ h 5 = μ m resistant against nitrogen blow

BCP 80 µm long scratch (~ 0.8 mm)

mean width 100 μ m, depth 1-2 μ m at one end peak $\Delta h = 10 \mu$ m



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OP of Nb samples (> µm) is suitable for fast quality control of processes

Results for polycrystalline samples:

- Particulates with $\beta_{E,max}$ > 15 must be removed by HPR and DIC
- Scratches with $\beta_{E,max}$ > 13 must be prevented by a more careful handling
- Grain boundaries (∆h ≈ µm), hills and holes are not harmful for EFE but probably cause magnetic field enhancement and limitation?
- Emitter density of EP/HPR Nb samples increases exponentially with field
- Correlation between EFE, SEM and OP of localized emitters difficult

Results and outlook for single crystalline samples:

- Mean surface roughness decreases exponentially with BCP layer removal
- Regular pit-like features and few defects found, influence on EFE ?
- Correlation between EFE, SEM and OP of localized emitters will be easier
- Activation of various types of emitters by heating will be investigated soon



